

A PROBE TIP AND METHOD OF MANUFACTURING TIPS AND PROBES FOR
DETECTING MICROCURRENT OR MICROFORCE

Abstract of the Disclosure

5 [0056] A full metal probe and a method of making the metal probe for electrical atomic force microscopy. In one embodiment, the method comprises manufacturing the full metal probe using two lithography steps. The step of etching thin membranes is dropped or eliminated to substantially reduce
10 the processing time. Thus, topside processing is sufficient. The probe and tip can be peeled off from the wafer using a metallisation procedure.

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